# Electron Beam Lithography Central Facility
# (Zeiss Sigma 300 + NPGS v9)

## Booking request form for internal users (from IIT Bombay)

| | | |
|---|---|---|
| 1 | Name | |
| 2 | Department | |
| 3 | Are you a facility TA? | |
| 4 | Will you require assistance for operating the system? | |
| 5 | Substrate material of your sample<br>(e.g. Si/SiO2, GaAs, Sapphire etc..) | |
| 6 | Approximate size of the sample<br>(max size 2cm x 2 cm) | |
| 7 | Electron Beam Resist type<br>(e.g. PMMA, HSQ…) | |
| 8 | Have you compiled the pattern with QCAD in your local PC/laptop ? | |
| 9 | Time required (1 slot = 3 hours) | |
| 10 | Confirm that the sample is free of any material that will outgass in vacuum (e.g. biological material, uncured resist etc) | |